	Туре	т. 4	Hits	Soansh Taret				
, .	TAbe		nics	Search Text	 ngs	Stamp	Comment s	
					USPA T; US-P GPUB			
1	BRS	L1	16	yang near nian.in.	EPO; JPO; DERW ENT;	2004/04/1 2 17:54	×	
			***************************************		IBM_ TDB			
					USPA T; US-P GPUB			
2	BRS	L2	27	wang near zhigang.in.	; EPO; JPO; DERW	2004/04/1 2 18:03		
					ENT; IBM_ TDB			
*					USPA T; US-P GPUB			
3	BRS	L3	54	(floating near gate near flash near memory).ti.	; EPO; JPO; DERW	2004/04/1 2 18:07		
	·				ENT; IBM_ TDB			
					USPA T; US-P GPUB			
4	BRS	L4		floating near gate near flash near memory	; EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:07	•	

	Typé	L	#	Hits	Search Text	DBs	Time Stamp	Comment
5	BRS	L5			(floating near gate near flash near memory) near25 (barrier)	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM TDB	2004/04/1 2 18:10	
6	BRS	L6			(floating near gate near3 electrode) near25 (barrier)	USPA T; US-P GPUB; EPO; JPO;	2004/04/1 2 18:10	
						DERW ENT; IBM_ TDB USPA		
7	BRS	 L7		1	(floating near gate near3-electrode) near25 (barrier) near15 (hard near mask)	T; US-P GPUB; ; EPO; JPO; DERW ENT;	2004/04/1 2 18:11	
		· :				IBM_ TDB USPA T; US-P		
8	BRS .	L8 .		7711 =	(floating near gate) or (electrode) near25 (barrier) near15 (hard near mask)	GPUB; EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:12	

	Туре	L	#	Hits	Search Text	DBs	Time Stamp	Comment
9	BRS	L9		27061	(floating near gate) or (electrode) near25 (barrier) near15 (hard near mask) near15 (sidewall\$1 or side near wall\$1)	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM TDB	2004/04/1 2 18:12	
10	BRS	L1(0		(floating near gate) or (electrode) near25 (barrier) near15 (hard near mask) near15 (sidewall\$1 or side near wall\$1) near15 (channel)	; EPO;	2004/04/1 2 18:13	
11	BRS	_ L1:	1		a = 1.	GPUB	2004/04/1 2 18:15	
12	BRS	L12	2	27059	(barrier) near15 (hard near mask) near15 (sidewall\$1) or (side near wall\$1) near15 (channel) near15 (tunnel near dielectric)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:16	

	Type	L	#	Hits	Search Text	DBs	Time Stamp	Comment
13	BRS	L1	3		(floating near gate) or (electrode) near25 (barrier) near15 (hard near mask) near15 (sidewall\$1) or (side near wall\$1) near15 (channel) near15 (reverse near tunnel near dielectric)	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:16	
14	BRS	L1	4	27022	(floating near gate) or (electrode) near25 (barrier) near15 (hard near mask) near15 ((sidewall\$1) or (side near wall\$1)) near15 (channel) near15 (reverse near tunnel near dielectric)	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM TDB	2004/04/1 2 18:17	
					or (electrode)) near25 (barrier) near15 (hard near	USPA T; US-P GPUB		
15	BRS	L1	5	1	(side near wall\$1)) near15 (channel) near15 (reverse near	EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:17	
16	BRS	L1	б	40 .	((floating near gate) or (electrode)) near25 (barrier) near15 (hard near mask) near15 ((sidewall\$1) or (side near wall\$1))	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:24	

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17	BRS	L17	677	((floating near gate) or (electrode)) near25 (barrier) near15 ((sidewall\$1) or (side near wall\$1))	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM TDB	2004/04/1 2 18:25	
18	BRS	L18	-	or (electrode)) near25 (barrier) near15 ((sidewall\$1) or (side near wall\$1)) near15	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:31	
19	BRS	L19	52	or (electrode)) near25 (barrier) near15 ((sidewall\$1) or (side near wall\$1) or (spacer\$1)) near15	USPA T; US-P GPUB; EPO; JPO; DERW ENT; IBM_ TDB	2004/04/1 2 18:35	
20	BRS	L20	3165	or (spaceral) hearts (channel)	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2004/04/1 2 18:36	

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21	BRS	L21	1235	or (electrode)) near25 ((sidewall'\$1) or (side near wall\$1) or (spacer\$1)) near15 (channel) near25 ((tunnel) or (insulat\$3 or dielectric))	USPA T; US-P GPUB; IPO; DERW ENT; IBM TDB	2004/04/1 2 19:09	
22	BRS	L22		or (electrode))	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2004/04/1 2 19:09	

		Ü	1	Document ID	Title	Current	OR	Pages	Issue Date
1		\	_	US 20030216042 A1	CMP slurry for oxide film and method of forming semiconductor device using the same	438/689		12	20031120
2				US 6660588 B1	High density floating gate flash memory and fabrication processes therefor	438/257	*	25	20031209
3			. 🗆	US 6617639 Bl	Use of high-K dielectric material for ONO and tunnel oxide to improve floating gate flash memory coupling	257/324		14	20030909
4	*			US 6274418. B1	Method of manufacturing flash memory cell	438/211		4	20010814